AMENDMENTS TO THE CLAIMS

Claim 1. (cancelled)

Claim 2. (currently amended) ~~The assembly of claim 1~~ A micromirror assembly, comprising: a micromirror having a reflective top surface and a bottom surface; a support member having a member end; and the support member end supporting the micromirror for controllable tilting relative to the member end, further comprising liquid positioned relative to the bottom surface such that capillary force of the liquid holds the micromirror on the support member.

Claim 3. (original) The assembly of claim 2 wherein the liquid has a low vapor pressure.

Claim 4. (original) The assembly of claim 3 wherein the low vapor pressure is less than 0.01 mm mercury at 25 degrees C.

Claim 5. (original) The assembly of claim 2 wherein the liquid is an oil.

Claim 6. (currently amended) The assembly of claim ~~1~~ 2 wherein the bottom surface has a centrally positioned depression and the end engages in the depression.

Claim 7. (currently amended) The assembly of claim ~~1~~ 2 wherein the end is a pointed end.

Claim 8. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror is able to pivot in any direction about an axis of the pointed end.

Claim 9. (currently amended) The assembly of claim ~~1~~ 2 wherein the bottom surface has a centrally positioned slot, and the end engages in the slot.

Claim 10. (currently amended) The assembly of claim ~~1~~ 2 wherein the end is an elongate edge deposed in the slot so that the micromirror can tilt about an axis of the slot.

Claim 11. (currently amended) The assembly of claim ~~1~~ 2 wherein the support member comprises a pin.

Claim 12. (currently amended) The assembly of claim ~~1~~ 2 wherein the support member ~~comprising~~ comprises a cone.

Claim 13. (currently amended) The assembly of claim ~~1~~ 2 wherein the support member ~~comprising~~ comprises a needle.

Claim 14. (currently amended) The assembly of claim ~~1~~ 2 wherein the end is made of sapphire.

Claim 15. (currently amended) The assembly of claim ~~1~~ 2 wherein the support end has a hardness greater than Mohs Scale 8.

Claim 16. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror has a round disc shape.

Claim 17. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror is symmetrical about its vertical axis.

Claim 18. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror has a diameter of generally between 100 and 200 microns.

Claim 19. (currently amended) The assembly of claim ~~1~~ 2 further comprising a beam source oriented so that an incident beam therefrom hits a center of the reflective surface.

Claim 20. (currently amended) The assembly of claim ~~1~~ 2 further comprising a beam source oriented so that an incident beam therefrom hits the reflective surface at a location spaced from a center of the reflective surface.

Claim 21. (currently amended) The assembly of claim ~~1~~ 2 further comprising a plurality of beam sources oriented so that their respective beams hit the reflective surface at different locations thereon.

Claim 22. (original) The assembly of claim 21 wherein each of the beam sources is an optical fiber.

Claim 23. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror is tiltable about two, three or four equally spaced axes perpendicular to an axis of the member end.

Claim 24. (currently amended) The assembly of claim ~~1~~ 2 wherein the micromirror is round and has a diameter of generally 200 micrometers.

Claim 25. (currently amended) The assembly of claim ~~1~~ 2 further comprising an electromagnet on a support surface below the bottom surface.

Claim 26. (original) The assembly of claim 25 wherein the electromagnet is sputtered on the support surface.

Claim 27. (original) The assembly of claim 25 wherein the electromagnet includes a sputtered core and a sputtered winding on the core.

Claim 28. (currently amended) The assembly of claim ~~1~~ 2 further comprising a magnet on the bottom surface.

Claim 29. (original) The assembly of claim 28 wherein the magnet coats the entire bottom surface.

Claim 30. (original) The assembly of claim 28 wherein the magnet is only on peripheral areas of the bottom surface.

Claim 31. (currently amended) ~~The assembly of claim 28~~ A micromirror assembly, comprising: a micromirror having a reflective top surface and a bottom surface; a support member having a member end; and the support member end supporting the micromirror for controllable tilting relative to the member end and a magnet on the bottom surface, wherein the magnet is a mixture of zumarium, cobalt and nickel.

Claim 32. (original) The assembly of claim 28 wherein the magnet is sputter coated on the bottom surface.

Claim 33. (original) The assembly of claim 28 wherein the magnet is a permanent magnet.

Claim 34. (original) The assembly of claim 28 wherein the magnet is an electromagnet.

Claim 35. (currently amended) ~~The assembly of claim 1~~ A micromirror assembly, comprising: a micromirror having a reflective top surface and a bottom surface; a support member having a member end; and the support member end supporting the micromirror for controllable tilting relative to the member end and further comprising a substrate, the support member being a horizontal elongate member, the elongate member having an elongate edge defining the member end, the bottom surface having an elongate upwardly-disposed surfaced, and the elongate edge being disposed in the upwardly-disposed surface.

Claim 36. (original) The assembly of claim 35 wherein the upwardly-disposed surface is a groove on the bottom surface.

Claim 37. (original) The assembly of claim 35 further comprising liquid in the upwardly-disposed surface which exerts a capillary holding action on the micromirror.

Claim 38. (original) The assembly of claim 35 further comprising electromagnets on either side of the elongate member to cause the micromirror to controllably tilt from side to side.

Claim 39. (original) The assembly of claim 38 further comprising a substrate, the elongate member being supported by and extending up from the substrate, and the electromagnets being supported on the substrate.

Claim 40-79 (Cancelled)